

## 2018 EUVL Workshop Keynote Talk

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*Abstract for talk to be published.*

### Presenting Author

Harry J. Levinson is Sr. Director of GLOBALFOUNDRIES's Strategic Lithography Technology organization and Sr. Fellow. Dr. Levinson also served for several years as the chairman of the USA Lithography Technology Working Group that participated in the generation of the lithography chapter of the International Technology Roadmap for Semiconductors. He is the author of two books, *Lithography Process Control* and *Principles of Lithography*. He holds over 60 US patents. Dr. Levinson is an SPIE Fellow, previously chaired the SPIE Publications Committee, and served on SPIE's Board of Directors. He has a BS in engineering from Cornell University and a PhD in physics from the University of Pennsylvania. His PhD thesis, titled *Resonances and Collective Effects in Photoemission*, addressed certain phenomenon involving the interactions of light and matter. For this work he received the Wayne B. Nottingham Prize in surface science.

